

### Claims

1. A hetero-interface field effect transistor comprising:  
a substrate; and  
a cation-polarity layered structure including at least a barrier layer and a channel layer wherein said barrier layer includes  $\text{In}_x\text{Al}_{1-x}\text{N}$ , x being in the range of about  $0 \leq x \leq 0.30$ .
2. The hetero-interface field-effect transistor according to claim 1 wherein said barrier layer includes  $\text{In}_{0.17}\text{Al}_{0.83}\text{N}$
3. The hetero-interface field-effect transistor according to claim 2 wherein said channel layer includes GaN
4. The hetero-interface field-effect transistor according to claim 2 wherein said channel layer includes  $\text{In}_y\text{Ga}_{1-y}\text{N}$ , y being in the range of about  $0 < y \leq 1$ .
5. The hetero-interface field-effect transistor according to claim 1 wherein said barrier layer includes  $\text{In}_x\text{Al}_{1-x}\text{N}$ , x being in the range of about  $0 \leq x < 0.17$ .
6. The hetero-interface field-effect transistor according to claim 5 wherein said channel layer includes GaN
7. The hetero-interface field-effect transistor according to claim 5 wherein said channel layer includes  $\text{In}_y\text{Ga}_{1-y}\text{N}$  ( $0 < y \leq 1$ ).
8. The hetero-interface field-effect transistor according to claim 1 wherein said barrier layer includes  $\text{In}_x\text{Al}_{1-x}\text{N}$ , x being in the range of about  $0.17 < x \leq 0.25$
9. The hetero-interface field-effect transistor according to claim 8 wherein said channel layer includes GaN.
10. The hetero-interface field-effect transistor according to claim 8 wherein said channel layer includes  $\text{In}_y\text{Ga}_{1-y}\text{N}$ , y being in the range of about  $0 < y \leq 1$ .

11. The hetero-interface field-effect transistor according to claim 1 wherein said barrier layer includes  $\text{In}_x\text{Al}_{1-x}\text{N}$ , x being in the range of about  $0.25 < x \leq 0.30$ .

12. The hetero-interface field-effect transistor according to claim 11 wherein said channel layer includes  $\text{In}_y\text{Ga}_{1-y}\text{N}$ , x being in the range of about  $0 < y \leq 1$ .

13. A hetero-interface field effect transistor comprising:  
a substrate; and  
a layered QW structure including at least a barrier layer and a channel layer providing the total two dimensional electron gas density of above  $n_{\text{total}} = 1.1 \times 10^{13} \text{ cm}^{-2}$ .

14. A portable telephone phone comprising the hetero-interface field effect transistor of claim 1 or 13.

15. A communication system comprising the hetero-interface field effect transistor of claim 1 or 13.

16. A low noise amplifier comprising the hetero-interface field effect transistor of claim 1 or 13.

17. A radar system comprising the hetero-interface field effect transistor of claim 1 or 13.

18. A sensor comprising the hetero-interface field effect transistor of claim 1 or 13.

19. An intermediate frequency amplifier comprising the hetero-interface field effect transistor of claim 1 or 13.

20. A direct broadcast satellite system comprising the hetero-interface field effect transistor of claim 1 or 13.

21. A satelite communication system comprising the hetero-interface field effect transistor of claim 1 or 13.

22. A method for fabricating a hetero-interface field effect transistor comprising:

providing a substrate; and

fabricating a layered QW structure including at least a barrier layer and a channel layer providing the total two dimensional electron gas density of above  $n_{total} = 1.1 \times 10^{13} \text{ cm}^{-2}$ .

23. A method for fabricating a hetero-interface field effect transistor comprising:

providing a substrate; and

fabricating a layered QW structure including at least a barrier layer and a channel layer wherein barrier layer includes  $\text{In}_x\text{Al}_{1-x}\text{N}$  where  $0 \leq x \leq 0.30$ .

24. A method using a hetero-interface field effect transistor in a communications system comprising:

(a) fabricating the hetero-interface field effect transistor using the steps of:

providing a substrate; and

fabricating a layered QW structure including at least a barrier layer and a channel layer wherein barrier layer includes  $\text{In}_x\text{Al}_{1-x}\text{N}$  where  $0 \leq x \leq 0.30$ ; and

(b) using the fabricated hetero-interface field effect transistor in the communications system.

25. A method using a hetero-interface field effect transistor in an electronic device comprising an electronic circuit including a hetero-interface field effect transistor using having a substrate; and a layered quantum well structure including at least a barrier layer and a channel layer providing a polarization-induced charge.

26. An electronic device utilizing a hetero-interface field effect transistor comprising a substrate, and a layered quantum well structure including at least a barrier layer and a channel layer providing a polarization-induced charge.

27. The hetero-interface field-effect transistor according to claim 26 wherein said channel layer includes GaN.

28. The hetero-interface field-effect transistor according to claim 26 wherein said channel layer includes  $\text{In}_y\text{Ga}_{1-y}\text{N}$ , y being in the range of about  $0 < y \leq 1$ .

29. The hetero-interface field-effect transistor according to claim 26 wherein said barrier layer includes  $\text{In}_x\text{Al}_{1-x}\text{N}$ , x being in the range of about  $0 \leq x < 0.17$ .

30. The hetero-interface field-effect transistor according to claim 29 wherein said channel layer includes GaN.